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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10085092	FILING DATE 03/01/2002	CLASS 392 219	SUBCLASS 118	GAU 3712 1725	EXAMINER Fugwa
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**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 2001-058266 03/02/2001
JAPAN 2001-059293 03/02/2001
JAPAN 2001-072317 03/14/2001

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO 07043.0020
Foreign priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	
Verified and Acknowledged Examiners's initials			

TITLE : Heat treatment apparatus using a lamp for rapidly and uniformly heating a wafer

U.S. DEPT. OF COMM/PAT. & TM-PTO-43EL (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg. Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner PREPARED FOR ISSUE Application Examiner	
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